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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/361,980
Filing Date: July 28, 1999
Applicant: Yasuaki Tsuzuki et al.
Group Art Unit: 1765
Examiner: Lynette T. Umez-Eronini
Title: Method of Etching Metallic Thin Film on Thin Film Resistor
Attorney Docket: 4041J-000439

E/A
L.T.U-E,
6/19/03

Director of the United States Patent and Trademark Office
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action mailed February 26, 2003, Paper No. 19, please amend and reconsider the above-referenced patent application as follows.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 7 of this paper.